



004887.P522  
050503/(TAV:dlr)

Patent

IN THE UNITED STATES PATENT AND TRADEMARK OFFICE

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MAY 12 2003  
TC 1700

In re application of:

Don E. Curry et al.

Application No.: 09/828,067

Examiner: Rudy Zervigon

Filed: April 6, 2001

Art Unit: 1763

Attorney Docket No.: 004887.P522

For: A WAFER PROCESSING  
APPARATUS HAVING A  
CHAMBER WITH AN UPPER  
WALL HAVING GAS SUPPLY  
OPENINGS FORMED THEREIN  
WHICH PROMOTE MORE EVEN  
PROCESSING OF A WAFER

#4B  
9/3/03  
mw

Commissioner for Patents  
U.S. Patent and Trademark Office  
P.O. Box 1450  
Alexandria, Virginia 22313-1450

AMENDMENT AND RESPONSE TO OFFICE ACTION

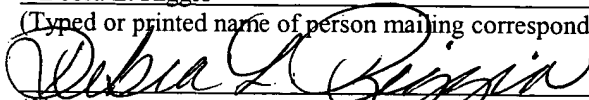
Sir:

In response to the Office Action mailed January 6, 2003, applicants respectfully request that the above-identified application be amended as follows:

I hereby certify that this correspondence is being deposited with the United States Postal Service as first class mail with sufficient postage in an envelope addressed to the Commissioner for Patents, U.S. Patent and Trademark Office, P.O. Box 1450, Alexandria, Virginia 22313-1450 on May 5, 2003.

Debra L. Riggio

(Typed or printed name of person mailing correspondence)

  
(Signature of person mailing correspondence)